

**Assignment-4**

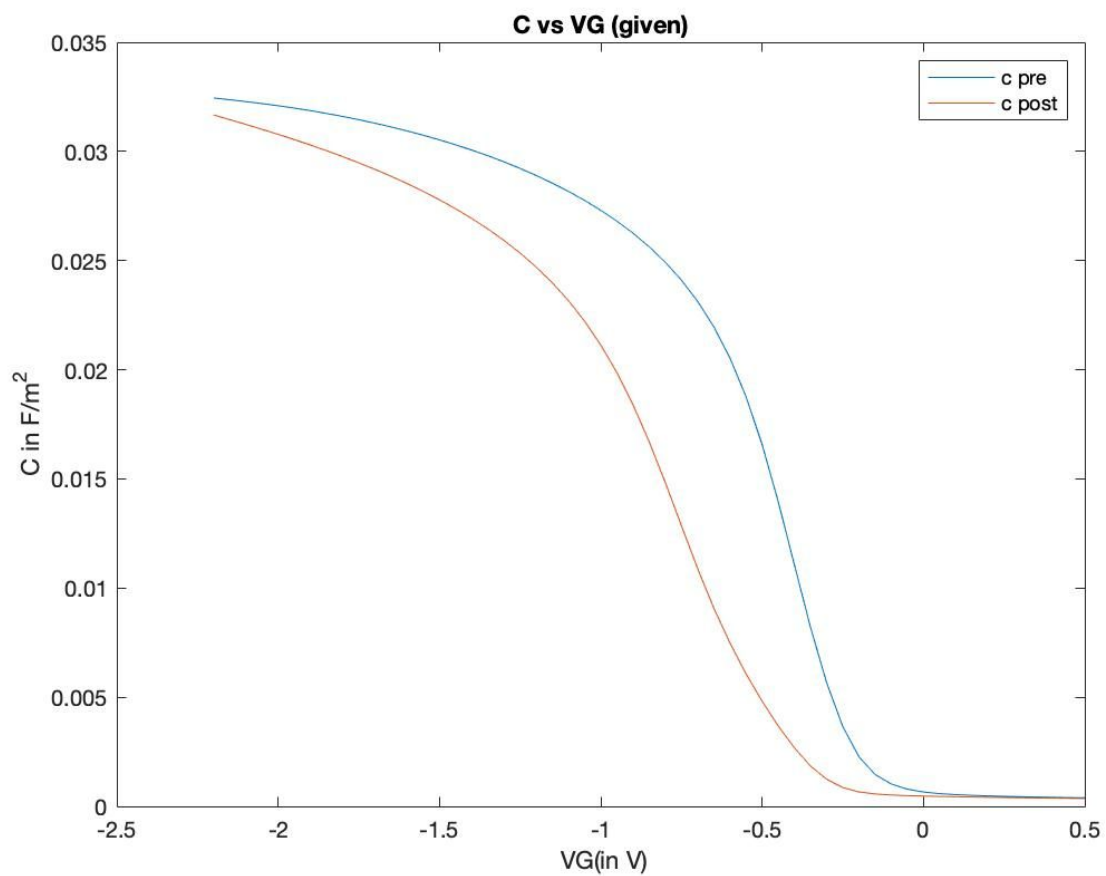
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Every parameter in graph is in **SI units**

Please insert the data in Data.m

As fabricated device is pre

And post stressed device is Post

DOPING:  $1.319009400000000\text{e}+22 / \text{m}^3$ 

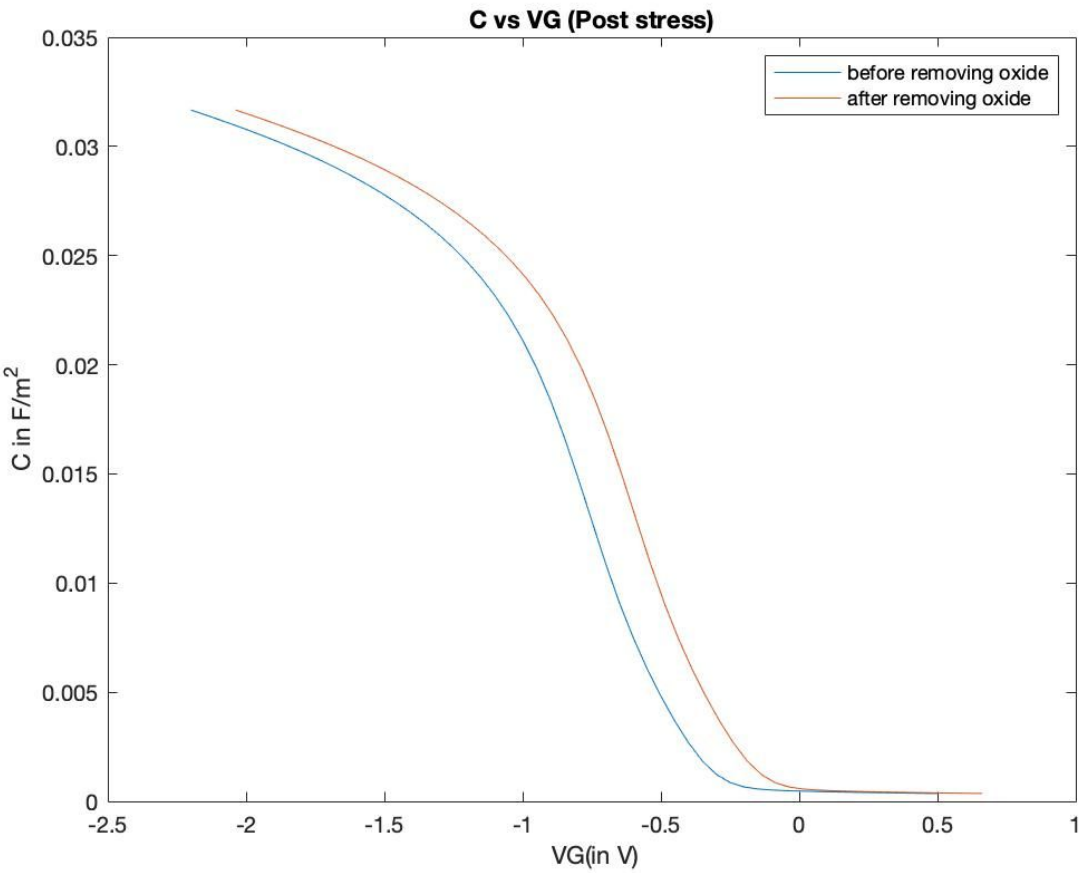
Cfb: 0.00273074294233495 SI units

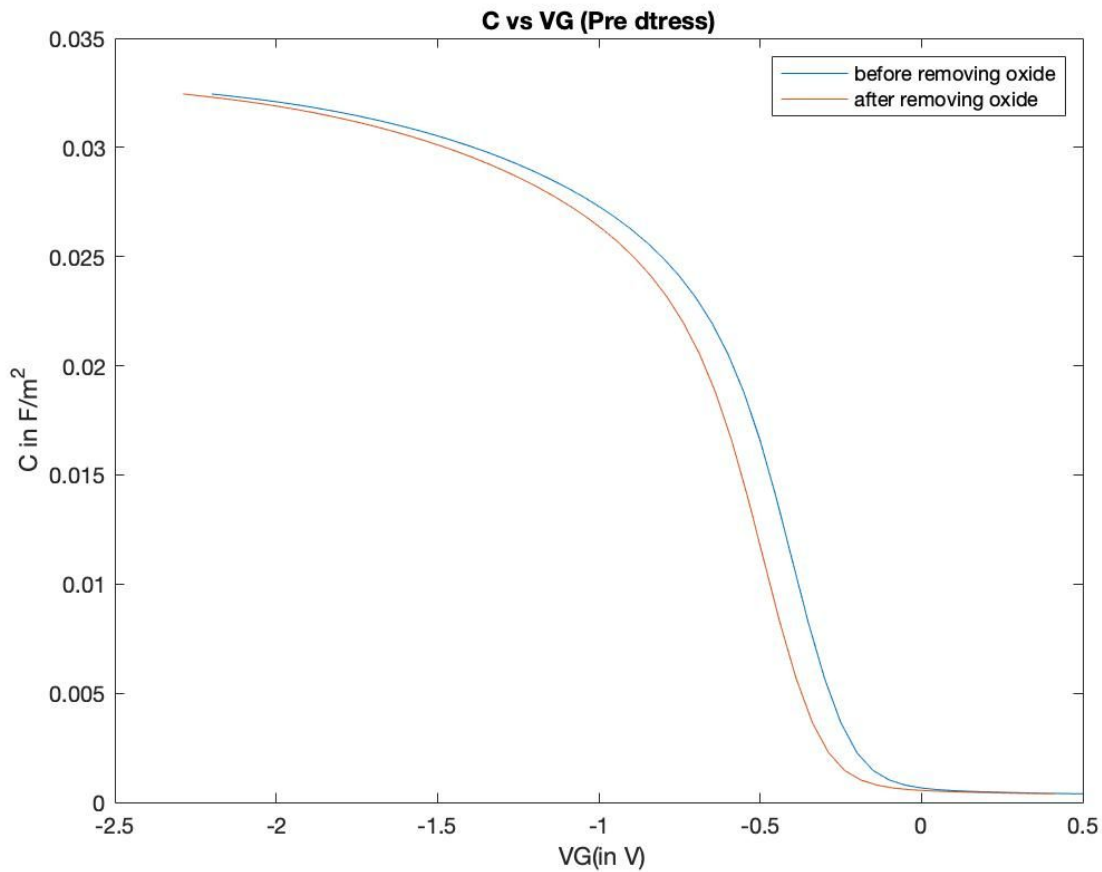
Cmg: 0.000552076339601112 SI units

	VFB(V)	VMG	VT
Ideal	-0.352309788957128	0.011959006637829	0.3699

Pre stress	-0.2000000000000000	0.1000000000000000	0.3620
Post stress	-0.4000000000000000	-0.1500000000000000	0.1620

Oxide charges:  
Pre stress:-0.00285682458541042 C  
Post stress:0.005255375414590 C





We can see from the below graph that the ideal curve touches curves with DIT even after mid band gap which should not be theoretically possible. Which may happen due to non idealities So to make the dit graph error free I have taken only the portion that has  $c_{low} = 7.5840e-04$  And  $c_{high} = 0.0310$  thus limiting the value of  $v_g$ . This again reduces the sweep of  $\phi_s$  available for DIT calculation.  
DIT formula used:

Check difference of real and reference  $V_{FB}$ ,  
calculate  $Q_{OX} + Q_{IT}$  (hence  $D_{IT}$ )

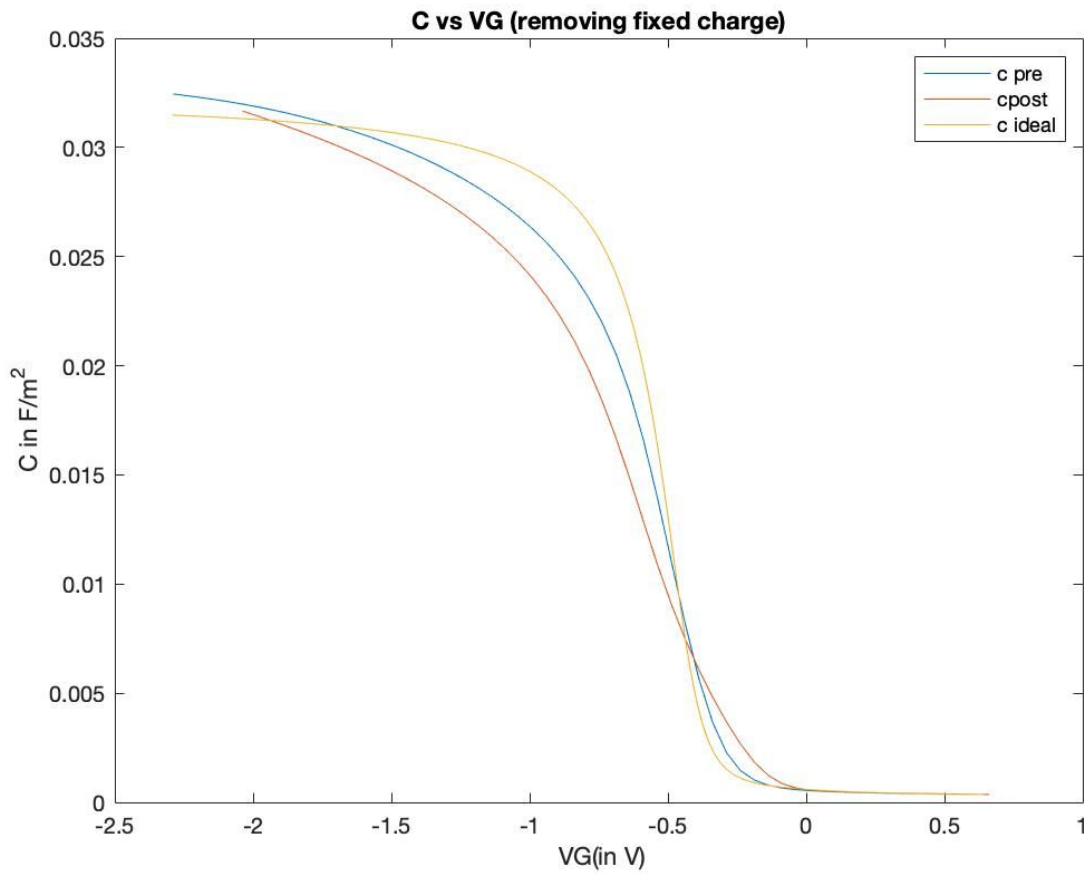
$$Q_{OX} + q \cdot D_{IT} \cdot \phi_F = C_{OX} \cdot \Delta V_{FB}$$

$Q_{OX}$  is the oxide trapped charge

Impact of thinner oxide is less when interface charge as  $\Delta V_{FB} = Q/C_{OX}$

Can repeat for different  $V_G$  values to get  $D_{IT}$  distribution in the bandgap (need to link  $V_G$  to band bending)

Replacing  $\phi_f$  with  $\phi_s$ .



DIT Profile:

After removing charge due to oxide layer we get the above graph. Now the charges are due to dit only. For each  $c$  we find  $\Delta V_G$  from the graph (ideal - post stress). From that we can find  $q$  due to Dit and which will be equal to  $q^* \text{dit} \cdot \Psi_s$ .  $\Psi_s$  will be corresponding to the  $V_G$  at that  $C$ .

